

Amendments to the Specification

Please amend paragraph [0018] as follows:

"[0018] Micropumps 12 employing the highly chemically stable material GaN have been fabricated using a photo-electro-chemical (PEC) etch technique that undercuts regions not masked by metallic overlayers. These pumps 12 have been shown to respond to electric fields by contraction along the direction of electric current flow due to the inverse piezoelectric effect. The plurality of micropumps are fabricated according to the description set out in copending application entitled "A METHOD OF MANUFACTURE OF A SUSPENDED NITRIDE MEMBRANE AND A MICROPERISTALTIC PUMP USING THE SAME", issued as U.S. Patent 6,579,068 on June 17, 2003 Ser. No. _____, filed on _____, which is incorporated herein by reference as if set out in its entirety."

Please amend paragraph [0023] as follows:

"[0023] Similarly, when probes 13 in the system of FIG. 1 are pressure sensors they can be fabricated according to the description set out in copending application entitled "A SEMICONDUCTOR NITRIDE PRESSURE MICROSENSOR AND METHOD OF MAKING AND USING THE SAME", U.S. Patent 6,647,796, issued Nov. 18, 2003, Ser. No. _____

_____, filed on _____, which is incorporated herein by reference as if
set out in its entirety."